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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Group Art Unit: 2812  
Examiner: Stanetta D. Isaac

In Re PATENT APPLICATION of:

Applicant(s): Jun KANAMORI

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SAC 6/20/06

Serial No.: 10/634,851

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Filing Date: August 6, 2003

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AMENDMENT

For: SEMICONDUCTOR DEVICE FABRICATION  
METHOD USING OXYGEN ION  
IMPLANTATION

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Atty. Ref.: MAE 292

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May 25, 2006

Please Enter

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Madam:

In response to the Examiner's Action mailed on February 28, 2006, please  
amend the above-identified application as follows: